



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Hwang et al.

Attorney Docket No.: KLA1P067/P995

Application No.: 10/672,298

Examiner: Patrick J. Connolly

Filed: September 26, 2003

Group: 2877

Title: METHOD AND APPARATUS USING

INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on December 27, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 2313-1450.

30 Alexandria, VA 2313-1

Signed:

Joyce L. rei

AMENDMENT :

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

It is respectfully submitted that the Examiner enters the following amendments in response to the Office Action dated 16 November 2005, a response to which is due on 16 February 2005.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begin on page 5 of this paper.

Remarks/Arguments begin on page 16 of this paper.